IN THE U.S. PATENT AND TRADEMARK OFFICE

November 3, 2003

ant(s):

Toshiaki MOTONAGA, et al

HALFTONE PHASE SHIFTING PHOTOMASK AND BLANKS FOR HALFTONE PHASE SHIFTING PHOTOMASK THEREFOR AND A METHOD FOR FORMING PATTERN BY USING THE HALFTONE

PHASE SHIFTING PHOTOMASK

Serial No. :

09/825 578

Group: 1756

Confirmation No.:

9940

Filed

April 3, 2001

Examiner:

S. Rosasco

Atty. Docket No.: OPS C-529

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Herewith is an amendment in the above-identified application.

Applicant claims small entity status. See 37 CFR 1.27.

[]The additional filing fee has been calculated as shown below:

	No.	No.	(X)	RATE	()		
For	Filed	Extra	LG Entity		SM Entity	Fee	<u> </u>
Basic Fee			\$770.00		\$385.00		\$0.00
Total Claims	(27 - 2	27 = 0)	x \$ 18.00		x \$ 9.00		0.00
Indep. Claims	(11 - 1	.1 = 0)	x \$ 86.00		x \$ 43.00		0.00
[] Multiple De	ep. Claim	ı	+ \$290.00		+ \$145.00		0.00
* * * TOTAL FILING FEE * * *						\$	0.00

- [X] Pursuant to 37 CFR 1.136(a), please extend the shortened period for response by two (2) month(s). The extension fee is: \$420.00.
- [X] A Check for \$420.00 is enclosed to cover fees.
- Please credit any overpayment, or charge any additional filing [X] fee required under 37 CFR 1.16 or 1.17 by this communication, to Deposit Account No. 06-1382. A duplicate copy of this sheet is enclosed.

IN DUPLICATE

MLM\pcq

Maki

CERTIFICATE OF MATLING

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on /

11/06/2003 FFRNREIA 00000096 09825578

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Mark L. Maki